

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

T. MORIMOTO et al

Serial No.

Filed: July 26, 2000

For: SCANNING PROBE MICROSCOPE AND METHOD OF MEASUREMENT

PRELIMINARY AMENDMENTAssistant Commissioner of Patents  
Washington, D.C. 20231

Sir:

Prior to the examination thereof, please amend the above-identified application as follows.

IN THE CLAIMS

Please amend claims 7, 13 and 24 as set forth below.

7. (Amended) A scanning probe microscope as set forth in [any one of] claim[s] 1 [to 6], wherein:

said probe has a high aspect ratio and said probe measures a surface with a high aspect ratio.

13. (Amended) A method of measurement of a scanning probe microscope as set forth in [any one of] claim[s] 8 [to 12], wherein: